

PATENT APPLICATION #2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hiroji AGA et al.

Application No.: New U.S. National Stage of  
PCT/JP03/16796

Filed: September 10, 2004

Docket No.: 121026

For: METHOD OF PRODUCING SOI WAFER AND SOI WAFER

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- ☒ 2. Relevance of references 2-3 and 7 is discussed in the present specification.
- ☒ 3. The references 1 and 4-6 were cited in a counterpart foreign application. An English language version of the foreign search report is attached for the Examiner's information.
- ☒ 4. The present application was filed or entered the U.S. National Stage of the PCT after June 30, 2003. In accordance with the June 11, 2003, Notice waiving the requirements of 37 CFR §1.98(a)(2)(i), copies of any U.S. patents and patent application publications are not attached.

- ☒ 5. English-language Abstracts of the non-English language references 2-4 are attached hereto.
- ☒ 6. A computer-generated English translation of the following Japanese references have been obtained from the website of the Japanese Patent Office (<http://www.jpo.go.jp>), and are attached, but have not been reviewed for accuracy. See References 2-4.

Respectfully submitted,



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<p>DEPOSIT ACCOUNT USE AUTHORIZATION Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461</p>
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Form PTO-1449 (REV. 8-83)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 121026		APPLICATION NO. New U.S. National Stage of PCT/JP03/16796	
INFORMATION DISCLOSURE STATEMENT  (Use several sheets if necessary)				APPLICANTS Hiroji AGA et al.			
				FILING DATE September 10, 2004			
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	
	1	US 6,372,609 B1	04/16/2002	Aga et al.			
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	
	2	JP B2 3048201 w/abstr. + trans.	03/24/2000	Japan			
	3	JP A 11-307472 w/abstr. + trans.	11/05/1999	Japan			
	4	JP A 10-242154 w/abstr. + trans.	09/11/1998	Japan			
	5	EP 1 158 581 A1	11/28/2001	Europe			
	6	WO 01/15215 A1	03/01/2001	WIPO			
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
	7	UCS Semiconductor Substrate Technology Workshop, "Science in Silicon," Realize publishers, pp. 443-496					
EXAMINER					DATE CONSIDERED		
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

Date: September 10, 2004